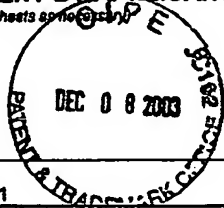


Substitute for form 1449A/PTO

**INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

**Complete if Known**

<b>Application Number</b>	10/081,818
<b>Filing Date</b>	February 20, 2002
<b>First Named Inventor</b>	Eldridge, Jerome
<b>Group Art Unit</b>	2818
<b>Examiner Name</b>	Ho, Tu-Tu

Sheet 1 of 1

Attorney Docket No: 1303.045US1

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Examiner Initials *	Cite No <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
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EXAMINER

Tu-Tu Ho

DATE CONSIDERED

Jan 2004

Substitute Disclosure Statement Form (PTO-1449)

\* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 908. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. 1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.